

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of:

Howard Ge, et al.

Serial No.: 10/680,960

Filed: October 7, 2003

Title: PHOTORESIST COATING PROCESS  
FOR MICROLITHOGRAPHY

Patent Examiner: Chacko Davis, Daborah

Group Art Unit: 1756

Confirmation No.: 6075

August 31, 2007

Costa Mesa, California 92626

**RESPONSE TO OFFICE ACTION**

Mail Stop RCE  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Responsive to the Office Action of June 1, 2007, kindly amend the above-identified application as follows: